Study of guard-ring design for Si-W wafer

Mustapha Benyamna, Rémi Cornat, Akli Karar, <u>François Morisseau</u> & Jean-Charles Vanel















Square Events

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Crosstalk

capacitance effect between guard-rings and wafer border pads.

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Study Overview

<u>Aim</u>:

test the previous hypothesis and evaluate different guard-ring options







• Set up

- Cu-Epoxy scale model
- General description
- 2 measurement protocols

Measurements

- First results
- Geometrical crosstalk distributions
- Impact of guard-ring positions

Conclusion

Cu - Epoxy



4 guard-ring options (4 layers each)



4 continuous

4 segmented 4 se



2 segmented 1 cm 2 continuous

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O COLO COLO O O O Injection and reading of signals through solder bonds

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2



(pad)

E

lnput (guard-ring)

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Injection and reading of signals through

µ-positioners.

^{µ-positioner} Binocular

ú

µ-positioner

ouțput

EM Shield

probehead

input

Calorimeter for I

E

probehead

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- + best electrical connections
- difficult to change the input or/and output position



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- + easy to change the input or/and output position
- + same as for real wafers
- EM radiations
- electrical connections not as good as they are with solder bonds



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3mm segmented guard-rings induce the lowest crosstalk. It is the best guard-ring option for preventing from square events.

The measurement method has been validated. The test bench is calibrated.

This study is just the first step, real 3x3 wafers will be measured as soon as we'll get them...







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